

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLICANT: M. Hatanaka et al. CONF. NO.: 8004
U.S. SERIAL NO.: 09/471,829 EXAMINER: P. Connolly
FILED: December 23, 1999 GROUP: 2877
FOR: APPARATUS AND METHOD FOR MEASURING THE THICKNESS
OF A THIN FILM VIA THE INTENSITY OF REFLECTED LIGHT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

AMENDMENT

Applicants are in receipt of the Office Action dated April 23, 2007 of the above-referenced application. Please amend the application as follows:

Amendments to the claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks begin on page 7 of this paper.

OK TO ENTER
PJC
07.07.2007